

SEVENTEENTH ANNUAL

BiTS

Burn-in & Test Strategies Workshop

TM

March 6 - 9, 2016

**Hilton Phoenix / Mesa Hotel
Mesa, Arizona**

Archive- Session 2

© 2016 BiTS Workshop – Image: Stiop / Dollarphotoclub

Presentation / Copyright Notice

The presentations in this publication comprise the pre-workshop Proceedings of the 2016 BiTS Workshop. They reflect the authors' opinions and are reproduced here as they are planned to be presented at the 2016 BiTS Workshop. Updates from this version of the papers may occur in the version that is actually presented at the BiTS Workshop. The inclusion of the papers in this publication does not constitute an endorsement by the BiTS Workshop or the sponsors.

There is NO copyright protection claimed by this publication. However, each presentation is the work of the authors and their respective companies: as such, it is strongly encouraged that any use reflect proper acknowledgement to the appropriate source. Any questions regarding the use of any materials presented should be directed to the author/s or their companies.

The BiTS logo and 'Burn-in & Test Strategies Workshop' are trademarks of BiTS Workshop.

Session 2

Ashok Kabadi
Session Chair

BiTS Workshop 2016 Schedule

Frontiers Day

Monday March 7 - 1:30 pm

Material Matters

"Long Life Probe Pin by Electroforming Process"

Makota Kondo & Hirotada Teranishi - Omron Corporation
Takahiro Sakai & Naoyuki Kimura - Omron Corporation

"Carbon Nanotube Polymer Composites as High Performance Thermal Interface Materials for Burn in and Test Applications"

Leonardo Prinzi - Georgia Institute of Technology
Craig Green & Baratunde Cola - Carbice Nanotechnologies, Inc.

"Requirements and Solutions for Test PCBs"

Markku Jamsa - Aspocomp Group Oyj

"PCB Test Fixture and Socket Challenges for mmWave Applications"

Don Thompson Jose - R&D Altanova
Jose Moreira - Advantest Europe GmbH
Giovanni Bianchi - Advantest

Long Life Probe Pin by Electroforming Process

**Makoto Kondo, Hirotada Teranishi
Takahiro Sakai, Naoyuki Kimura**

OMRON Corporation

**ELECTRONIC AND MECHANICAL COMPONENTS COMPANY
CONNECTOR DIVISION**



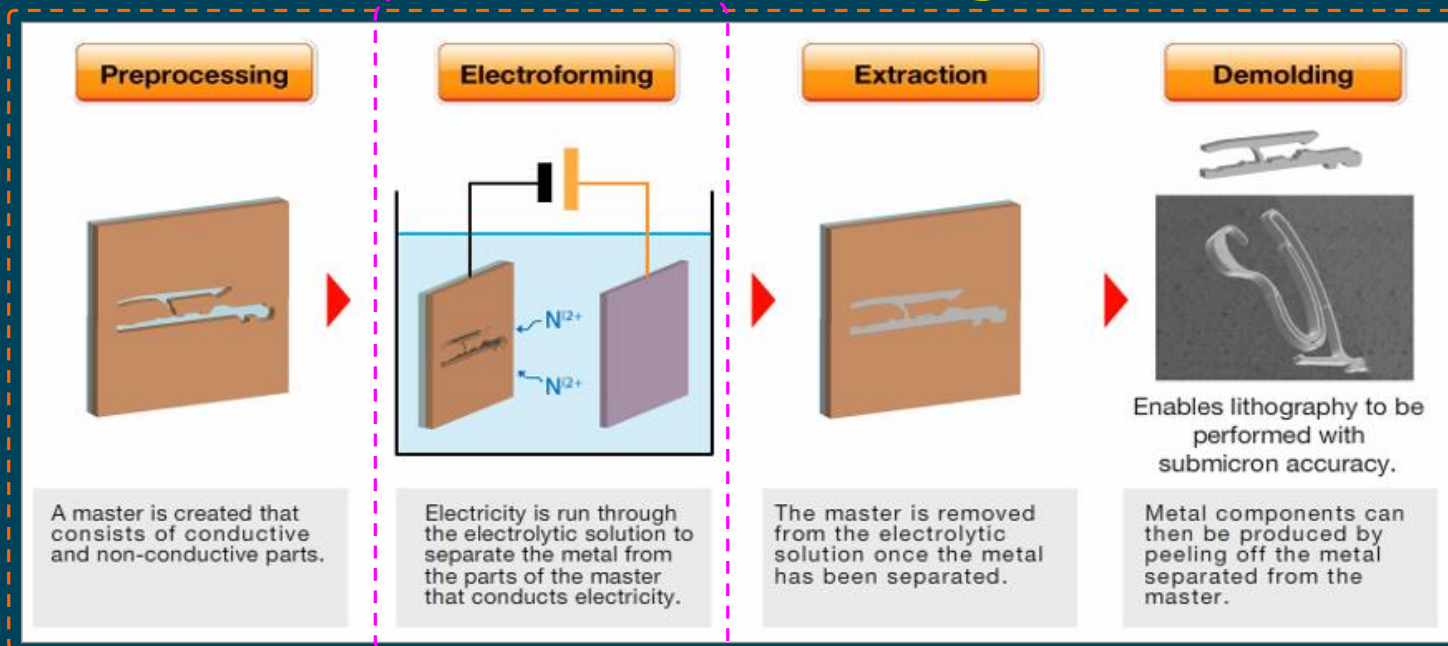
**2016 BiTS Workshop
March 6 - 9, 2016**



Agenda

- What is Electroforming Process
- Characteristic of Electroforming Process
- Development to Probe Pins
- Unique Head Shape for Au Plated Pad
- Basic Study for Solder Ball Test
- Conclusion

What is Electroforming Process



Feature

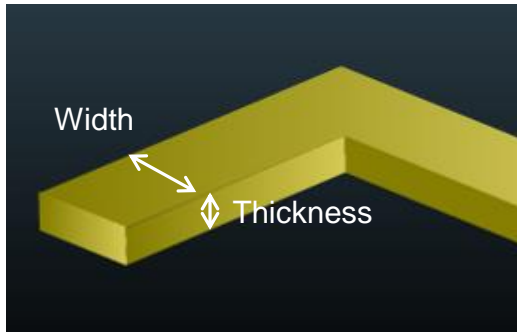
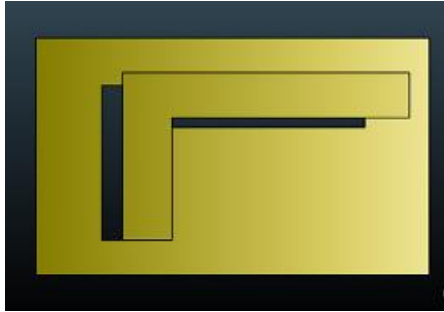
1. Possible to make high precision micro profile which have never been made by traditional press work.
2. Easy and speedy trial sample providing because of lower investment than traditional press work.

Characteristic of Electroforming Process

【Micro-Profile Fabrication Technology -High Aspect Ratio-】

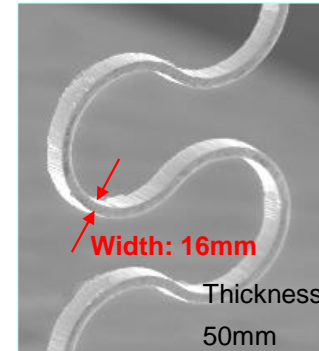
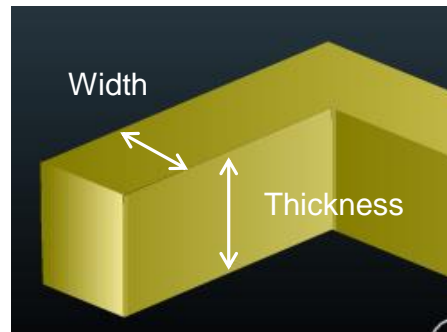
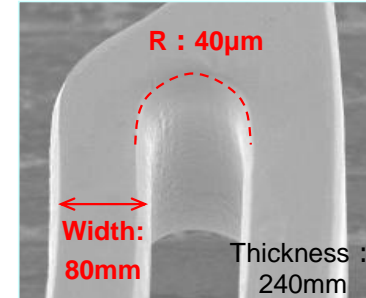
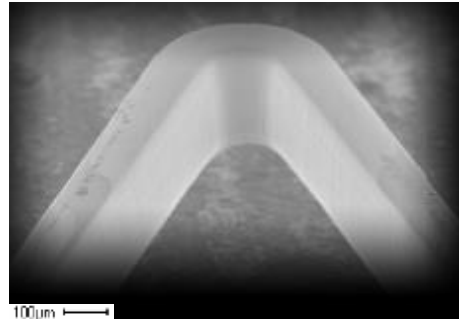
Possible to fabricate 30mm width work with high aspect ratio 1/3

Press Work / Etching Work



$Width \geq Thickness$
Aspect Ratio (T/W) = 1


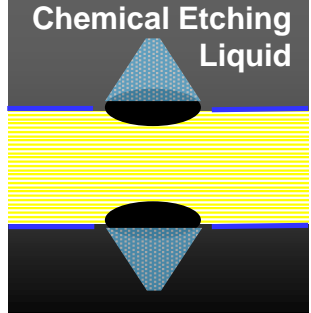
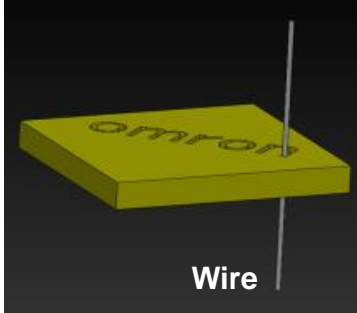
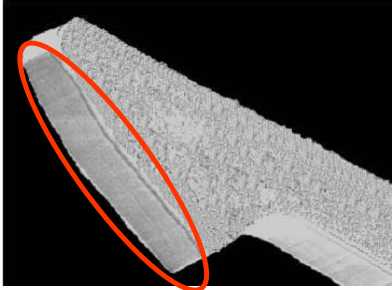
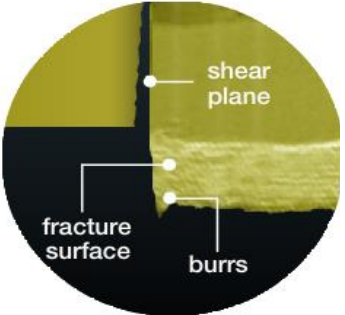
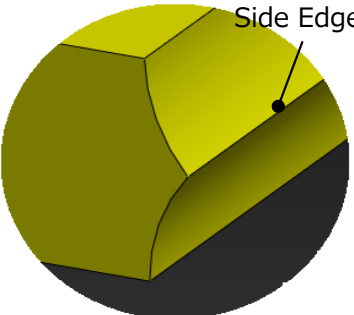
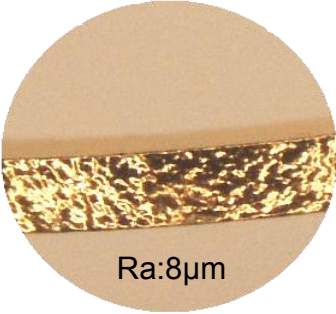
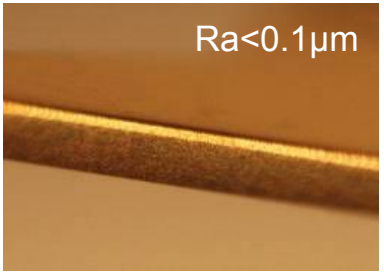
Electro Forming



$Width = Thickness \times 1/3$
Aspect Ratio (T/W) = 3

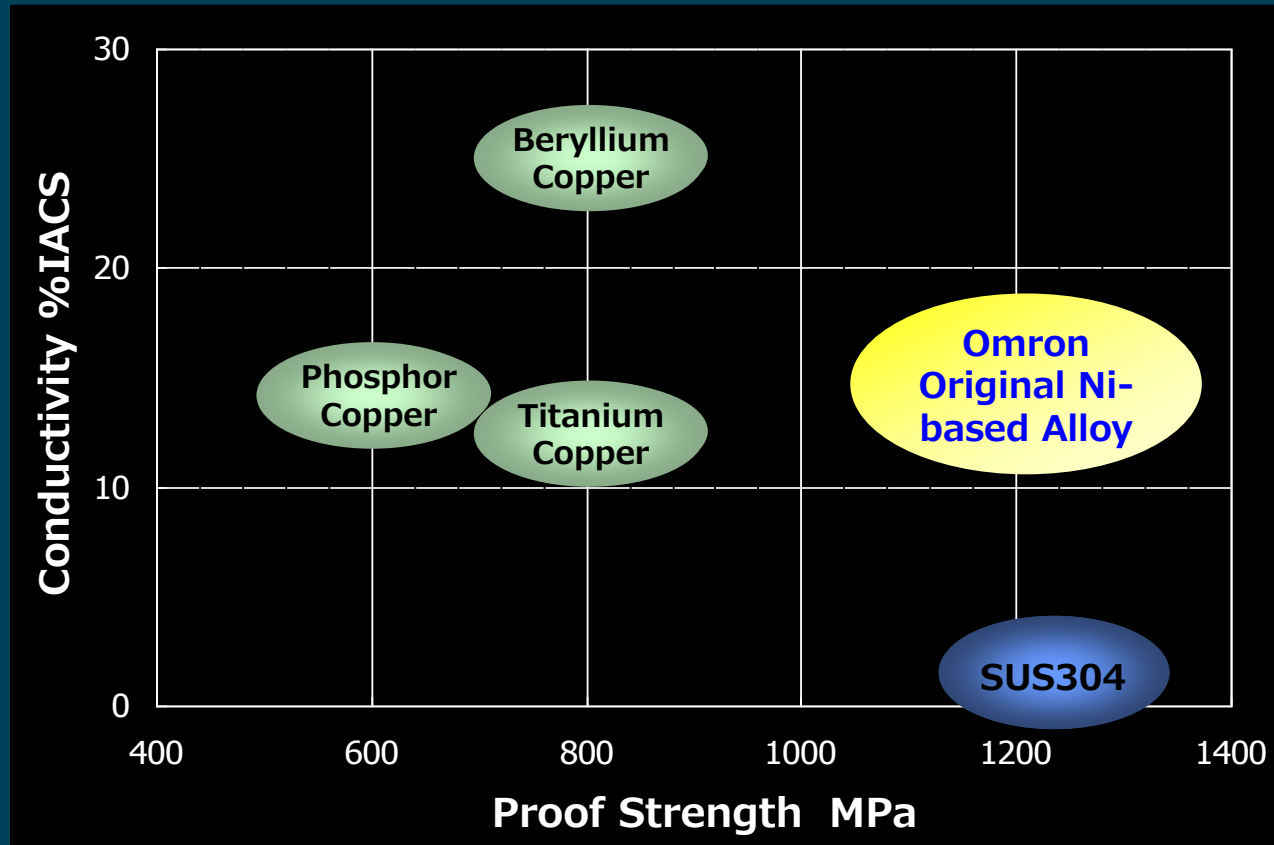
【Micro-Profile Fabrication Technology -Smooth Surface-】

Possible to fabricate end of Ra<0.1μm

Press Work	Etching Work	Wire Cut	Electroforming
			
			
Fracture /Burrs	Unnecessary Side Edge	Ra:3~10μm at 4 th cut	Smooth Surface at all planes

【Unique Material】

Originally Blended Material :
Mechanical SUS-level / Electrical Copper alloy



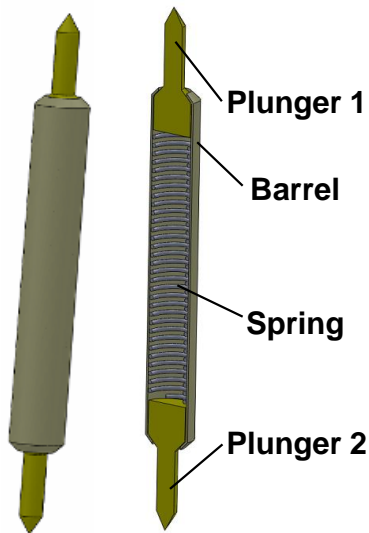
※ Proof stress: Stress not to cause plastic deformation

Long Life Probe Pin by Electroforming Process

Development to Probe Pins

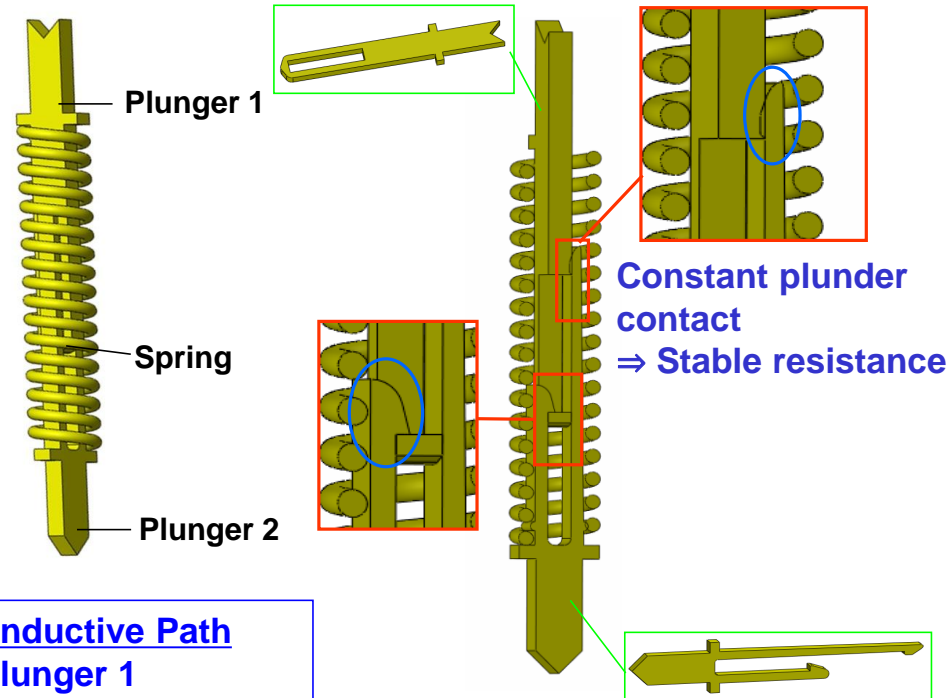
- Stable resistance by microfabrication relay structure
- High durability by smooth flat
- Compatible with socket for conventional probe pin

General Probe Pin



Conductive Path
Plunger 1
⇒ Tube
⇒ Plunger 2

Electroformed Probe Pin



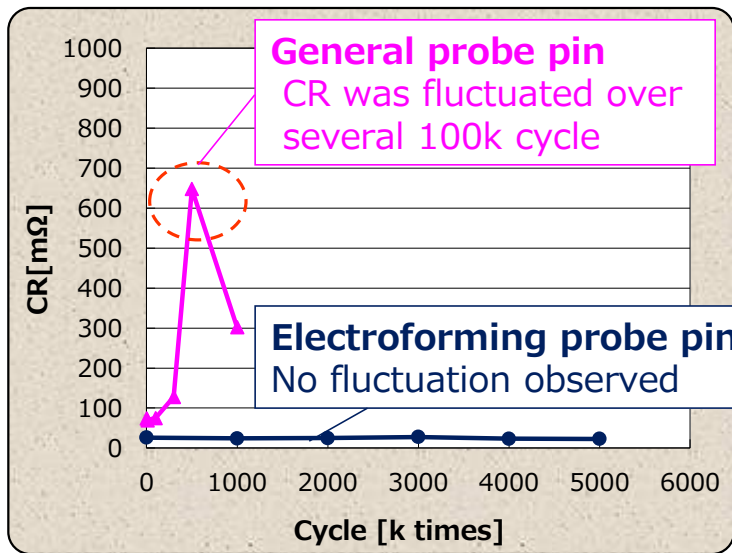
Conductive Path
Plunger 1
⇒ Plunger 2

【Electroformed Probe Pin vs General Probe Pin –Durability Test-】

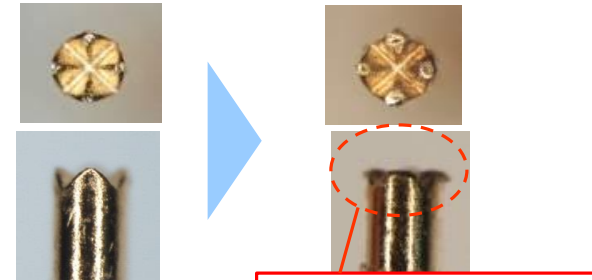
Test Condition

DUT: Au plated PAD
Temp: 20±5 degree C

Test Result



General probe pin

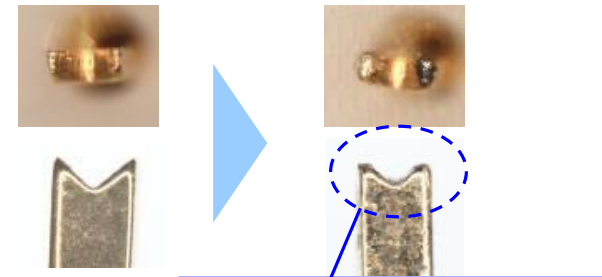


Broken crown end

Before Test

After Test

Electroforming probe pin



Almost no deformation

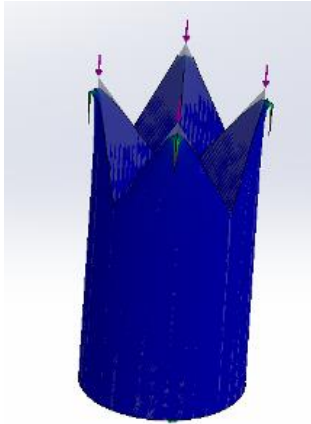
Before Test

After Test

【Mechanism of Long Life】

- Executed simulation of deformation amount at three conditions

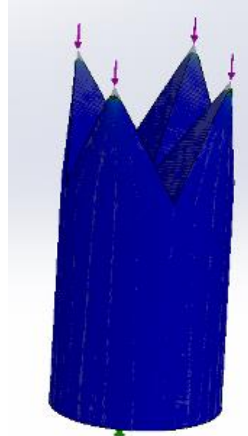
100gf at 4 points



Crown Profile
Material: Be-Cu (120GPa)

Deformation: 72µm

100gf at 4 points

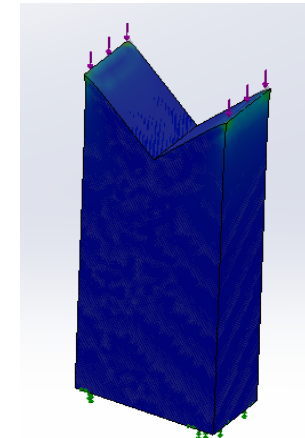


Crown Profile
Material: Ni Alloy(180Gpa)

Deformation: 40µm

Electroforming

200gf at 2lines



Plane Profile
Material: Ni Alloy(180Gpa)

Deformation: 4µm

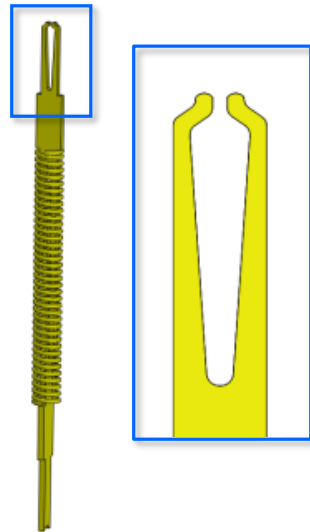
- Material strength \propto 1/deformation \Rightarrow Low deformation at high material strength
- Line contact leads stress dispersion \Rightarrow Low deformation at line contact

Unique Head Shape for Au Plated Pad

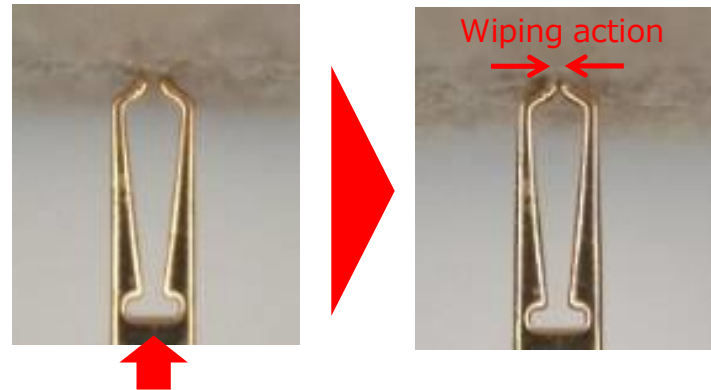
【Wiping Probe Pin】

Removal of foreign material by unique two arm wiping probe tip

Probe Tip Shape



Mechanism



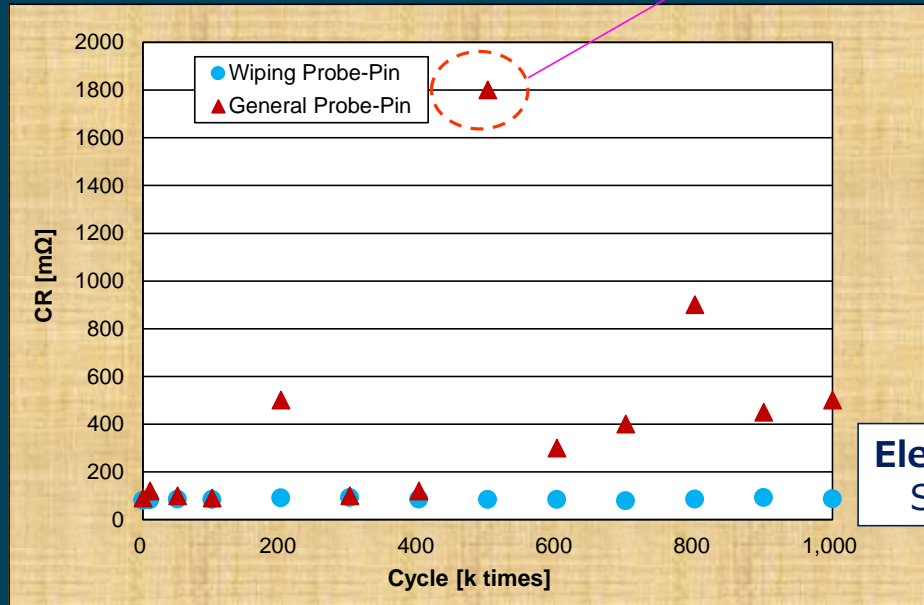
Contact probe tip with pad and add force
=>Horizontally moving on pad surface
=>Wipes foreign material on pad surface
=>Contacts on fresh surface

【Wiping Probe Pin vs General Probe Pin –Contact Reliability-】

Test Condition

DUT: Au plated PAD
Temp: 20±5 degree C

General probe pin
Significant deterioration
has been observed.



Electroforming probe pin
Stable contact at 1M cycles.

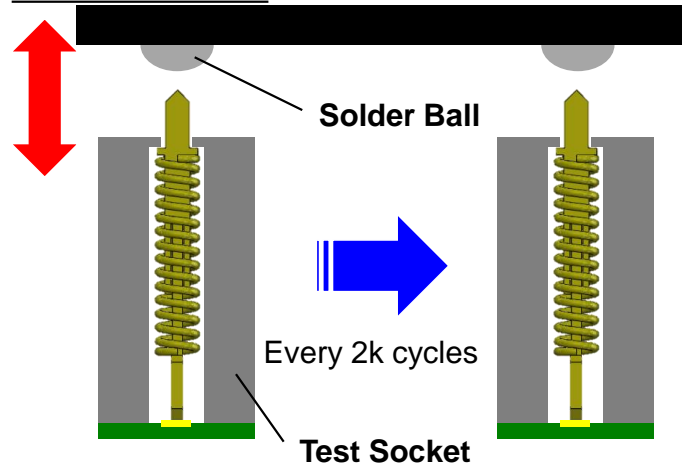
Electroformed probe pin can improve contact reliability by unique wiping probe tip

Basic Study for Solder Ball

【Purpose and Test Method】

Purpose : To derive the most suitable contact force and tip shape

Test Method



- Room Temperature
- Apply 0.1A current at every contact.
- Change the solder ball per 2k cycles.

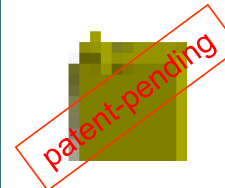
Tip Shape



Crown
(General Probe Pin)



Single

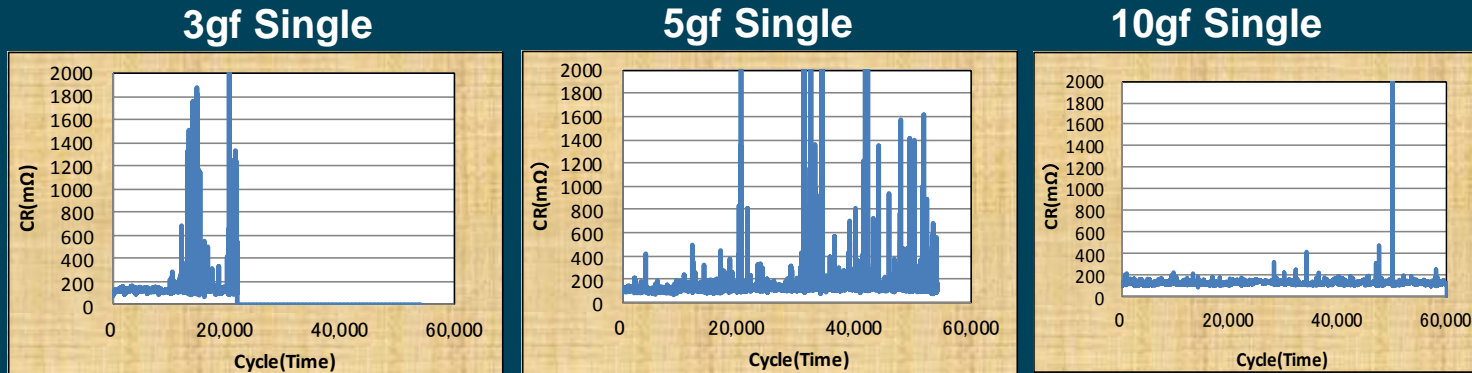


Wiping

Criteria

Over 200mΩ CR is measured at 100 times per 2k cycles (5%)

【Test Result -Influence of Load-】



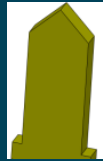
Contact Force	3gf	5gf	10gf	25gf
Crown			60,000 times or more	14,000 times
Single			14,000 times	32,000 times

Most suitable contact force is 10gf for each tip shape

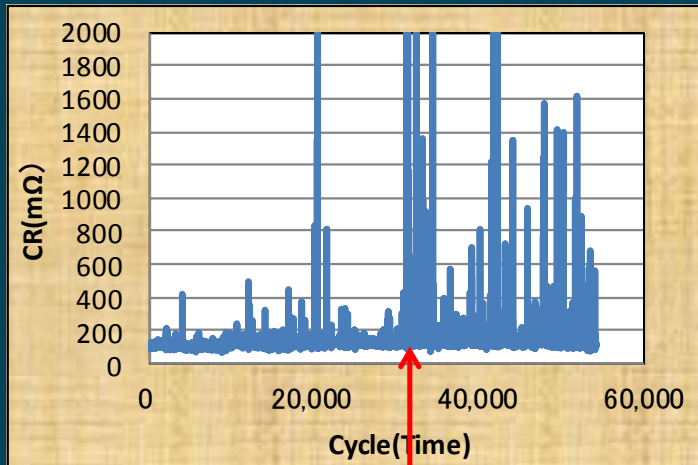
■ Supposed Mechanism

- Low Contact Force Region** : A spark due to oxide layer causes lower durability
- Suitable Contact Force Region** : Able to break oxide layer and less solder adhere
=> Keep good contact reliability
- High Contact Force Region** : Able to break oxide layer, but much solder adhere
=> Causes lower durability

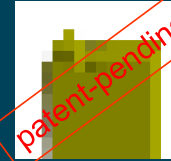
【Test Result -Influence of Tip Shape-】



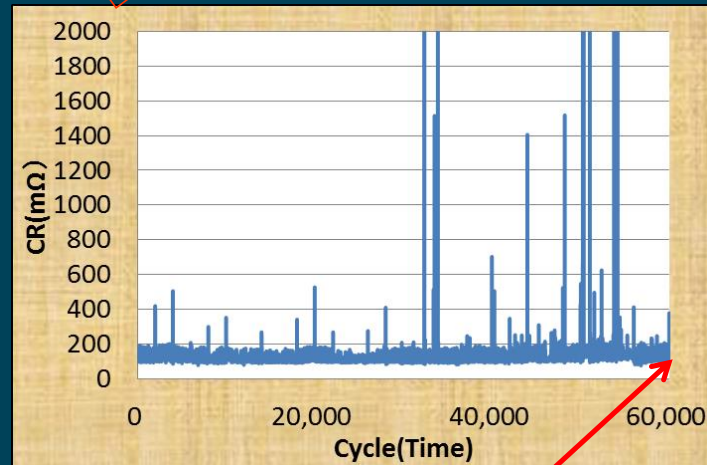
5gf Single



32,000 times



5gf Wiping



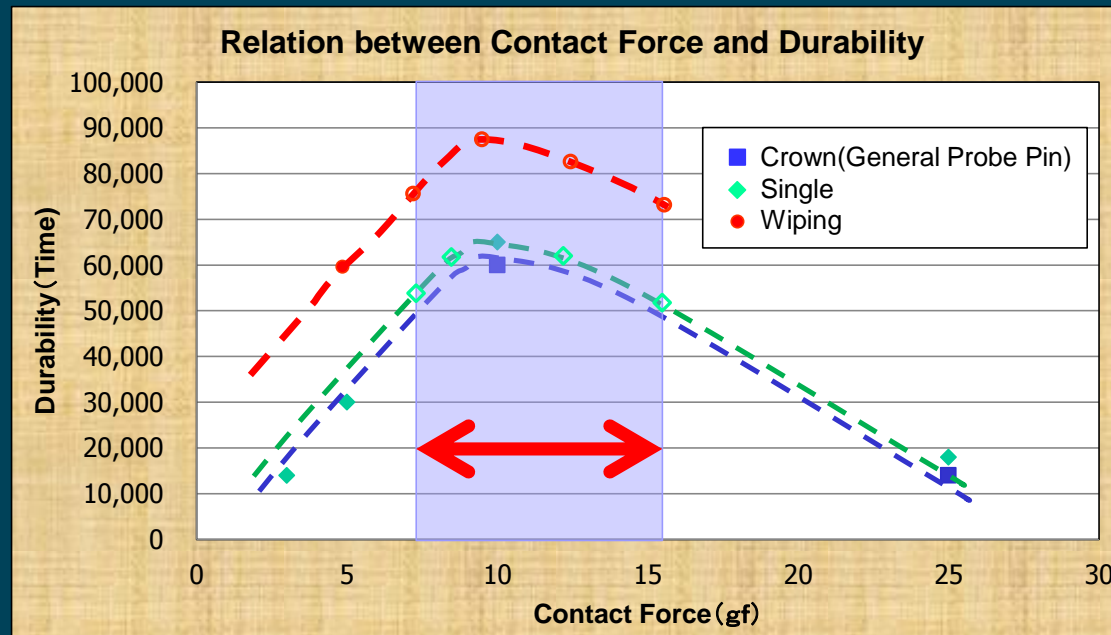
60,000 times or more

■ Supposed Mechanism

Wiping tip : Remove oxide layer by wiping shape and have wide contact area
=> Improve durability even at low contact force

【Future Work】

- Add the contact force point to seek the suitable range.
- Increase the number of data to improve the data reliability.
- Analyze the mechanism between contact resistance and solder adhesion.



Conclusion

- Features of electroforming process provide probe pin with stable contact resistance and high durability.
- Good contact reliability with Au plated pad is achieved by wiping probe tip.
- Basic study show a path toward suitable contact force range and tip shape for solder ball.